Atomic Layer Deposition platform in Luxembourg – review of emerging applications for sensors, MEMS, energy harvesters, transparent electronics and coated powder for composites



Figure 1 - Controlled of the wurtzite ZnO (002) orientation by thermal ALD on polymer and metal surfaces to obtain a strain sensor based on a diode junction. The SEM cross-section (left) detailed the red profile on the SEM top view micrograph (right) of the sensor microstructured in our cleanroom facilities (Courtesy: J. Polesel).

